

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

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APPLICANT
Hong-Da LIU

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GROUP

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U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
T.R.C.	3,930,857	1/6/1976	Bendz et al.	430	313	
	5,111,240	5/5/1992	Boetiger et al.	355	53	
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	5,596,618	1/21/1997	Ogushi	378	034	
	5,648,860	7/15/1997	Ooi et al.	349	10	
	5,777,713	7/7/1998	Kimura	349	156	
	5,978,062	11/2/1999	Liang et al.	349	155	
	6,028,659	2/22/2000	Kaneko	355	053	
	6,043,496	3/28/2000	Tennant	250	492	
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	6,236,445B1	5/22/2001	Foschaar et al.	319	156	

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

T.R.C.	K. Ismail, "A noel method for submicron structurization using optical projection lithography", Microelectronic Engineering Vol.1, No. 4, pp. 295-300 (1983).
	M.J. Cole et al., "Moving fiber/phase mask-scanning beam technique for enhanced flexibility in producing fibre gratings with uniform phase mask", Electronic Letter, 17th Aug. 1995, Vol. 31, No. 17, pp. 1488-1490 (1995).
	O. Tabata et al., "Moving mask Liga (M ² LIA) process for control of side wall inclination", Micro-Electro Mechanical System, 1999, MEMS 1999, The 12 th IEEE International Conference, pp. 252-256 (1999).
EXAMINER	DATE CONSIDERED 09/25/03

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.